

O P E I J C 66  
APR 14 2003  
PATENT & TRADEMARK OFFICE  
Docket No.: P2001,0011

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Alfred Kersch  
Applic. No. : 10/047,814  
Filed : January 15, 2002  
Title : Reaction Chamber for Processing a Substrate Wafer, and Method for Operating the Chamber

ASSOCIATE POWER OF ATTORNEY

Hon. Commissioner of Patents and Trademarks,  
Washington, D.C. 20231

Sir:

Please recognize MARKUS NOLFF (Reg. No. 37,006) as my associate in the matter in the above-identified application, with full powers. Please continue addressing all communications to the following address:

Lerner and Greenberg, P.A.  
P.O. Box 2480  
Hollywood, Florida 33022-2480

Respectfully submitted,

For Applicant

Date: April 8, 2003

LAURENCE A. GREENBERG  
REG. NO. 29,308

Lerner and Greenberg, P.A.  
Post Office Box 2480  
Hollywood, FL 33022-2480  
Tel: (954) 925-1100  
Fax: (954) 925-1101

/bmb

RECEIVED  
APR 16 2003  
TECHNOLOGY CENTER 2800